

Notice of References Cited	Application/Control No. 10/602,417	Applicant(s)/Patent Under Reexamination WALKER, DEAN M.	
	Examiner Meredith C. Petravick	Art Unit 3671	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2,313,590	03-1943	SHERER JR JOSEPH S; et. al.	56/15.7
*	B	US-3,921,372	11-1975	Arnbloek, Lennart Oswald	56/12.8
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	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kota et al., Design of Compliant Mechanisms: Applications to MEMS, found at www.engin.umich.edu/labs/csdl/papers/dsignofcm.pdf on April 24, 2006.
	V	What are Compliant Systems? found at http://www.flxsys.com/comp-sys.shtml on April 24, 2006.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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